Special Issue

Advances in Optical Instrument and Measurement Technology

Message from the Guest Editors

In recent years, with the development of laser sources, measurement approaches and new materials, many new technologies or applications of measurement and new optical instruments have appeared. Therefore, this Special Issue is intended for the presentation of new ideas and experimental results in the field of high-performance optical instruments and measurement technology. Potential topics include, but are not limited to: optical design, fabrication and testing; ultrafast optic development; computational optical imaging; analog image processing with optical metasurfaces and metamaterials; novel techniques in microscopy; fiber-optic sensors; laser measurement; digital holographic metrology and sensing; micro- and nanophotoelectric measurement.

Guest Editors

Prof. Dr. Zhan Gao

Dr. Jiakun Li

Dr. Qixin He

Deadline for manuscript submissions

closed (20 April 2025)

Applied Sciences

an Open Access Journal by MDPI

Impact Factor 2.5
CiteScore 5.5

mdpi.com/si/180463

Applied Sciences
Editorial Office
MDPI, Grosspeteranlage 5
4052 Basel, Switzerland
Tel: +41 61 683 77 34
applsci@mdpi.com

mdpi.com/journal/applsci

Applied Sciences

an Open Access Journal
by MDPI

Impact Factor 2.5
CiteScore 5.5

mdpi.com/journal/applsci

About the Journal

Message from the Editor-in-Chief

As the world of science becomes ever more specialized, researchers may lose themselves in the deep forest of the ever increasing number of subfields being created. This open access journal Applied Sciences has been started to link these subfields, so researchers can cut through the forest and see the surrounding, or quite distant fields and subfields to help develop his/her own research even further with the aid of this multi-dimensional network.

Editor-in-Chief

Prof. Dr. Giulio Nicola Cerullo
Dipartimento di Fisica, Politecnico di Milano, Piazza L. da Vinci 32,
20133 Milano, Italy

Author Benefits

Open Access:

free for readers, with article processing charges (APC) paid by authors or their institutions.

High Visibility:

indexed within Scopus, SCIE (Web of Science), Ei Compendex, Inspec, CAPlus / SciFinder, and other databases.

Journal Rank:

JCR - Q2 (Engineering, Multidisciplinary) / CiteScore - Q1 (General Engineering)